

# PI s stem

## PI s stem algorithm development that use modulating laser

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Key words : Modulating Laser, ESPI, LabVIEW, GPIB, Wavelength Modulation

1.

$\beta$  Wavelength(656.5nm),ref-  
ractive index(=3.5), refractive-index differential(  $10^{-3}/$  ),  
thermal resistance(R 25 )

, MEMS, LCD, Build-Up PCB

$$\beta = \frac{\lambda}{\alpha} \frac{\partial}{\partial T} \quad 6 \times 10^{-3}(\text{nm/}^\circ\text{C}) \quad (6)$$

(ESPI)

PZT

2.2. PI

PZT

RS-232 i

$\Omega$

$\Omega$

PZT

2.

### 2.1 Wavelength Modulation

current)

(wave length)

(injection

$$\Delta i = \alpha \cdot \Delta T \quad (\text{wavelength})$$

NI

PCI-GPIB

= GPIB  
LabVIEW 8.2

$$\Delta \lambda = \beta \cdot \Delta i = \beta \cdot \alpha \cdot \Delta T \quad (1)$$

(Laser cavity condition)

$$\lambda = \frac{2L}{m} \quad (2)$$

: Refractive index

: Cavity length

$m$  : Integer

$$\Delta T = \frac{\Delta \lambda}{\beta \cdot \alpha}$$

$$\Delta T = R \cdot \Delta i \quad (3)$$

: Thermal resistance

$$\Delta \lambda = \frac{2L}{m} \left( \frac{\partial \lambda}{\partial T} + \frac{\partial \lambda}{\partial i} \right) \cdot \Delta T \quad (4)$$

(cavity length)

(refractive index)

$$\Delta \lambda = \frac{2L}{m} \left( \frac{\partial \lambda}{\partial T} + \frac{\partial \lambda}{\partial i} \right) \cdot \Delta T \quad (5)$$

3.



Fig. 1 Modulating GPIB program

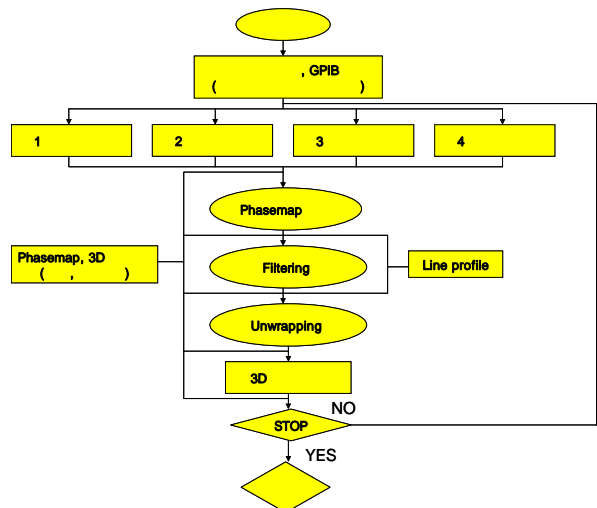


Fig. 2 Modulating Laser method algorithm

4. n

300 X 160 mm, 2mm

ESPI

Beam Splitter

ESPI

GPiB

USB

. n

Table. 1

5 μ m, 5.5 μ m, 6 μ m

80mA

Pig3~8

+0.2mA +0.4mA  
unwrapping, 3D

Pasemap  
λ

3D 1Pix 2 μ m

3D

+0.2mA

+0.4mA

+0.1mA +0.3mA  
Pasemap



Fig. 6 Phase map, Unwrapping, 3DPolt (+0.4mA, 5.5 μ m)

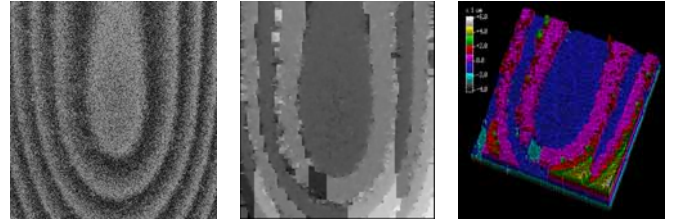


Fig. 7 Phase map, Unwrapping, 3DPolt (+0.2mA, 6 μ m)

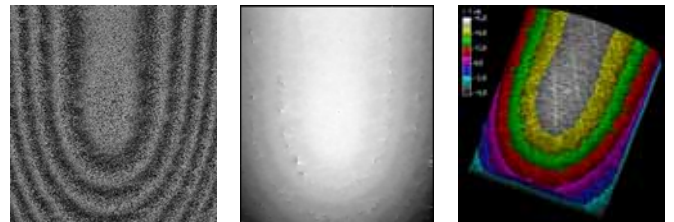


Fig. 8 Phase map, Unwrapping, 3DPolt (+0.4mA, 6 μ m)

Table.1. Error rats by Experiments Data

		μ	. μ	μ
.2m		4.31	4.72	5.11
		13.8%	13.6%	14.8%
.4m		4.73	5.21	5.67
		5.4%	5.2%	5.5%

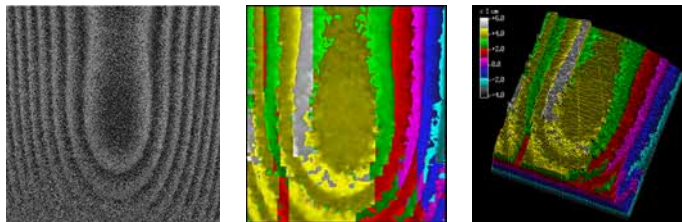


Fig. 3 Phase map, Unwrapping, 3DPolt (+0.2mA, 5 μ m)

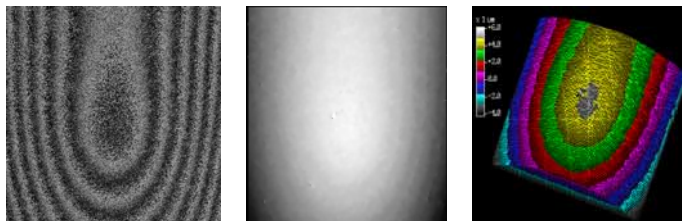


Fig. 4 Phase map, Unwrapping, 3DPolt (+0.4mA, 5 μ m)



Fig. 5 Phase map, Unwrapping, 3DPolt (+0.2mA, 5.5 μ m)

GPiB controller LabVIEW 8.2  
ESPI System

unwrapping ESPI  
3D

+0.4mA

λ

detail

ESPIS System PZT

= LabVIEW 8.2

λ

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